

WEST**Freeform Search**

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12 and microelectromechanical

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JPAB,EPAB,DWPI	photoresist and (etch\$ or pattern) and oxide and mask\$ and (micromechanical)	0	<u>L6</u>
JPAB,EPAB,DWPI	photoresist and (etch\$ or pattern) and oxide and mask\$ (((438/723 438/734 438/736 438/743 438/753 438/756 438/942)!.CCLS.) and photoresist and etch\$ and oxide and mask\$	3019	<u>L5</u>
USPT	((438/723 438/734 438/736 438/743 438/753 438/756 438/942)!.CCLS.)	528	<u>L4</u>
USPT	((438/723 438/734 438/736 438/743 438/753 438/756 438/942)!.CCLS.)	1279	<u>L3</u>
USPT	(((216/41 216/47 216/79 216/80 216/97 216/99)!.CCLS.)) and photoresist and etch\$ and oxide and mask\$	475	<u>L2</u>
USPT	((216/41 216/47 216/79 216/80 216/97 216/99)!.CCLS.)	2323	<u>L1</u>